

# 290. PTB-Seminar

## VUV and EUV Metrology

PTB Berlin

Abstr. 2-12  
10587 Berlin

Poster List

Poster Session Thursday 05.11.2015

13:00 - 14:15

No.	First author	Title	Institute/Company
<b>VUV and EUV instrumentation</b>			
1	E.F. Barte	Soft X-ray generation under the action of pico and nanosecond laser pulses on nano-structured target	TU Prague
2	R. Lokasani	XUV emission from highly ionized plasmas of 2nd transition row elements, irradiated by Q-switched N	TU Prague
3	J. van Veldhoven	Towards a contamination-tolerant EUV power sensor	TNO
4	L. Rodriguez-de Marcos	VUV reflectometer for in-situ measurement of coatings	CSIC
5	M. Tryus	A spatially resolving non-destructive tool for multi-angle EUV spectroscopic reflectometry	RWTH
6	J. Bußmann	Coherent diffractive imaging for actinic inspection with EUV light produced by a laboratory-scale gas discharge radiation source	RWTH
7	A. Sokolov	An XUV At-Wavelength Metrology facility at BESSY-II	HZB
8	F. Nawaz	Capillary discharge based soft X-ray imaging setup, using Fresnel zone plate (FZP) optics	TU Prague
9	D. Wilson	Laboratory-based photoemission spectro-microscopy at 71.7 eV for studies of complex materials	FZJ
<b>Optics &amp; Materials</b>			
10	P. Pennartz	Recent Developments for X-ray Optics, from EUV to hard X-Rays	Rigaku
11	O. Hofmann	Investigation of Luminescent Materials for EUV Metrology Applications	RWTH
12	A. Comisso	Optical Properties of TiO2 thin films from soft x-ray reflectivity measurements	U Padova
13	F. Liu	EUV induced secondary electron emission on HfO2, SnO2, and Ru thin films	MESA+
14	A. Zameshin	Free-form approach to reconstruct periodic multilayer structure from X-Ray reflectivity	U Twente
15	E. Darlatt	Degradation of organic thin films by UV/VIS irradiation investigated by UPS and XPS	PTB
16	T. Siefke	VUV wire grid polarizer based on interband absorption	FSU
<b>Detectors</b>			
17	A. Sorokin	Gas-monitor detectors for x-ray FELs	DESY
18	V. Zabrodskaa	SIPM for direct VUV registration	Ioffe
19	V. Zabrodskaa	VUV detector based on SiC	Ioffe
<b>Scatter techniques</b>			
20	S. Burger	FEM Maxwell solver for EUV and X-ray scattering applications	JCMwave
21	H. Groß	Impact of different LER patterns on scattered light intensities	PTB
<b>Post-Deadline Posters</b>			
22	F. Melsheimer	Combination of discharge- and laser-produced plasmas for high brightness extreme ultraviolet (EUV) light sources	FZ Jülich
23	I. Makhotin	GISAXS analysis of "delayed nitridation" 6.x nm multilayers	U Twente